

Molecular Beam Epitaxy and Electronic Structure of Atomically Thin Oxyselenide Films

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Atomically thin oxychalcogenides have been attracting intensive attention for their fascinating fundamental properties and application prospects. $\text{Bi}_2\text{O}_2\text{Se}$, a representative of layered oxychalcogenides, has emerged as an air-stable high-mobility 2D semiconductor that holds great promise for next-generation electronics. The preparation and device fabrication of high-quality $\text{Bi}_2\text{O}_2\text{Se}$ crystals down to a few atomic layers remains a great challenge at present. Here, molecular beam epitaxy (MBE) of atomically thin $\text{Bi}_2\text{O}_2\text{Se}$ films down to monolayer on SrTiO_3 (001) substrate is achieved by co-evaporating Bi and Se precursors in oxygen atmosphere. The interfacial atomic arrangements of MBE-grown $\text{Bi}_2\text{O}_2\text{Se}/\text{SrTiO}_3$ are unambiguously revealed, showing an atomically sharp interface and atom-to-atom alignment. Importantly, the electronic band structures of one-unit-cell (1-UC) thick $\text{Bi}_2\text{O}_2\text{Se}$ films are observed by angle-resolved photoemission spectroscopy (ARPES), showing low effective mass of $\approx 0.15 m_0$ and bandgap of ≈ 0.8 eV. These results may be constructive to the synthesis of other 2D oxychalcogenides and investigation of novel physical properties.

Thanks to their rich physics and fascinating application prospects, atomically thin metal oxides/chalcogenides (sulfide, selenide, or telluride) and their heterostructures, such as transition metal dichalcogenides (TMDs),^[1,2] superconducting β -phase FeSe ,^[3,4] topological insulator (Bi_2Se_3 , Bi_2Te_3),^[5,6] and $\text{LaAlO}_3/\text{SrTiO}_3$,^[7,8] have been attracting tremendous interest

over decades. Oxychalcogenides, which can be regarded as mixing and bridging chalcogenides and oxides together, reactivate their research booms for the remarkable phenomena such as high carrier mobility,^[9] thermoelectricity,^[10–12] ferroelectricity,^[13] and superconductivity.^[14] $\text{Bi}_2\text{O}_2\text{Se}$, a representative of oxychalcogenides family, emerged as an air-stable high-mobility layered semiconductor, which holds promise for next-generation digital devices and optoelectronics.^[2,9,13,15–23] For example, the bulk $\text{Bi}_2\text{O}_2\text{Se}$ crystals show an ultrahigh Hall mobility of $\approx 280\,000\text{ cm}^2\text{ V}^{-1}\text{ s}^{-1}$ at low temperature^[9] and robust bandgap (immune to Se vacancies) after cleavage.^[17] Nanoplates and thin films of $\text{Bi}_2\text{O}_2\text{Se}$ were successfully prepared by chemical vapor deposition (CVD),^[9,15,21,23] displaying excellent switching behavior of $I_{\text{on}}/I_{\text{off}}$ and high Hall mobility (up to $450\text{ cm}^2\text{ V}^{-1}\text{ s}^{-1}$) at

room temperature. Outstanding optoelectronic properties were recently observed in CVD-grown $\text{Bi}_2\text{O}_2\text{Se}$ nanoplates.^[16,18,23–25] The present research is mainly focused on the bulk crystals and few-layer or multilayer samples due to the challenge to faithfully achieve the growth of atomically thin $\text{Bi}_2\text{O}_2\text{Se}$ films. The atomically thin counterpart down to one-unit-cell (1-UC)

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thickness will provide an excellent 2D platform to investigate the physical properties different from bulk one due to quantum size effect. Compared to CVD method, molecular beam epitaxy (MBE), a state-of-the-art technique with ultrahigh vacuum (UHV) environment, has obvious advantages for precise thickness control owing to ultralow growth rate with a 2D growth mode.^[26,27] Additionally, the UHV condition ensures the ultra-clean surface of the samples, which will facilitate the direct observation of electronic structures of atomically thin films.

Here, for the first time, we exploited the MBE-growth of atomically thin $\text{Bi}_2\text{O}_2\text{Se}$ films down to monolayer (ML) by co-evaporating Bi and Se precursors in oxygen atmosphere. By precisely controlling the growth condition such as flux rates of each components and growth temperature, a 2D growth mode of $\text{Bi}_2\text{O}_2\text{Se}$ was achieved on (001)-oriented SrTiO_3 (STO) substrate. Besides, with the assistance of atomically resolved scanning transition electron microscopy (STEM) and energy-dispersive spectroscopy (EDS), the atomic structures at $\text{Bi}_2\text{O}_2\text{Se}/\text{STO}$ interface were unambiguously revealed, showing a highly crystalline structure of layered $\text{Bi}_2\text{O}_2\text{Se}$, atomically sharp interface and atom-to-atom alignment in $\text{Bi}_2\text{O}_2\text{Se}/\text{STO}$. Importantly, the electronic band structures of MBE-grown 1-UC thick $\text{Bi}_2\text{O}_2\text{Se}$ films were successfully revealed by angle-resolved photoemission spectroscopy (ARPES), showing low effective mass of $\approx 0.15 m_0$ and a bandgap of ≈ 0.8 eV. The very slightly bandgap enlarging of 1-UC $\text{Bi}_2\text{O}_2\text{Se}$ compared to bulk one indicates weak quantum size effects exists in $\text{Bi}_2\text{O}_2\text{Se}$, which is consistent with the previous generalized gradient approximation (GGA) calculations.^[9]

Figure 1a shows the preparation of atomically thin $\text{Bi}_2\text{O}_2\text{Se}$ films by a home-made oxide MBE facility, and more details about film growth are described in the Supporting Information. In our growth, Bi and Se elements are evaporated using standard effusion cells, and oxygen is imported in the chamber through a leakage valve for precisely control the oxygen flow rate. Single polished Nb-doped STO single crystals with excellent conductivity and high thermal stability are chosen as the epitaxial substrates. The utility of Nb-doped STO substrate allows the direct characterization of surface-sensitive tools such as ARPES, where the samples are required to be placed on a conducting substrate. More importantly, as shown in

Figure 1b,c, cubic perovskite oxide STO ($a = 3.90$ Å) provides reasonable lattice matching ($\approx 0.5\%$ mismatch) with $\text{Bi}_2\text{O}_2\text{Se}$ that has a tetragonal crystal structure ($I4/mmm$, $a = 3.88$ Å, $c = 12.16$ Å, $Z = 2$). Before epitaxial growth of $\text{Bi}_2\text{O}_2\text{Se}$ films, the STO (001) substrates are pretreated in UHV at 950 °C for 1 h to obtain single TiO_2 -terminated surface.^[3] Typical atomic force microscopy (AFM) image of the prepared STO (001) substrate surface shows clear terraces with an identical step height of 0.4 nm (Figure 2a), which is consistent with the height of one-unit cell (0.39 nm) of STO (001).

The key to MBE-grown atomically thin $\text{Bi}_2\text{O}_2\text{Se}$ film is the precise control of substrate growth temperature (T_s), Se/Bi flux ratio and oxygen pressure in the MBE system. In detail, we adjust T_s by following the common “three-temperature method,” which means T_s is set between the evaporation temperatures of Bi and Se (namely $T_{\text{Bi}} > T_s > T_{\text{Se}}$). Under the condition of $T_s > T_{\text{Se}}$, the residual Se will desorb spontaneously from the surfaces to prevent codeposition or bulk crystal growth.^[28] Besides, relatively lower Se/Bi flux (< 10) and higher oxygen pressure ($> 10^{-5}$ mbar) will suppress the formation of Bi_2Se_3 impurities, and pure $\text{Bi}_2\text{O}_2\text{Se}$ phase will be obtained.^[29–32] In our case, the pure $\text{Bi}_2\text{O}_2\text{Se}$ phase can be obtained when Se and Bi flux rates are kept at 7 and 3 Å min^{-1} , respectively, calibrated by quartz crystal microbalance (QCM). It is worth mentioning that there are no other oxygen-rich secondary phases, such as Bi_2O_3 or SeO_2 , found in all our attempts to parameter optimization. We found that the optimized MBE growth of atomically thin $\text{Bi}_2\text{O}_2\text{Se}$ occurs at $T_s = 290$ °C under an oxygen pressure of 1×10^{-4} mbar, since relatively high growth temperature would result in multilayer growth, while relatively low temperature might lead to 3D growth (Figure S1, Supporting Information). As indicated in Figure 2b, at the initial growth stage, monolayer $\text{Bi}_2\text{O}_2\text{Se}$ islands preferentially nucleate along the terraces of STO substrate and form discontinuous 2D islands with irregular edges. With the growth coverage increasing, these isolated monolayer islands merge together and form continuous ML film that covers the STO (001) substrate surface completely and strictly follows the terrace structure (Figure 2c). Monolayer $\text{Bi}_2\text{O}_2\text{Se}$ is defined as half unit cell with the thickness of ≈ 0.6 nm, which consists of one complete Bi_2O_2 layer plus one complete Se layer.

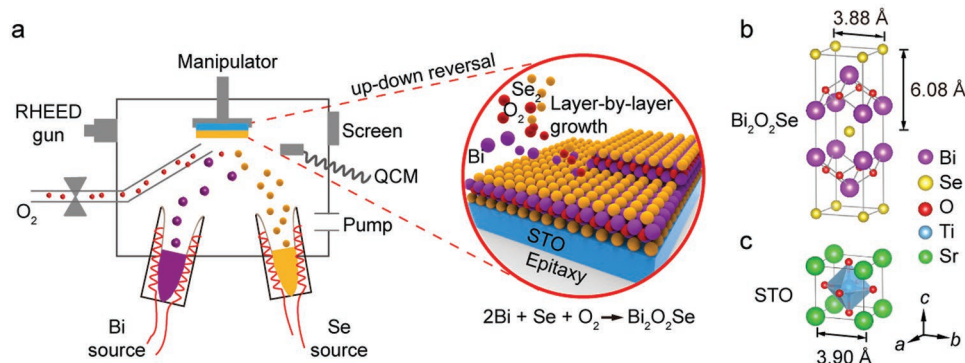


Figure 1. a) Schematic diagram of epitaxial growth of atomically thin $\text{Bi}_2\text{O}_2\text{Se}$ films on a (001)-oriented SrTiO_3 (STO) substrate by co-evaporating the Bi and Se precursors in oxygen atmosphere in a home-made MBE setup equipped with reflective high-energy electron diffraction (RHEED) and quartz crystal microbalance (QCM). b,c) Crystal structures of $\text{Bi}_2\text{O}_2\text{Se}$ and STO, respectively, showing negligible lattice mismatch in ab plane and the same in-plane crystal symmetry.

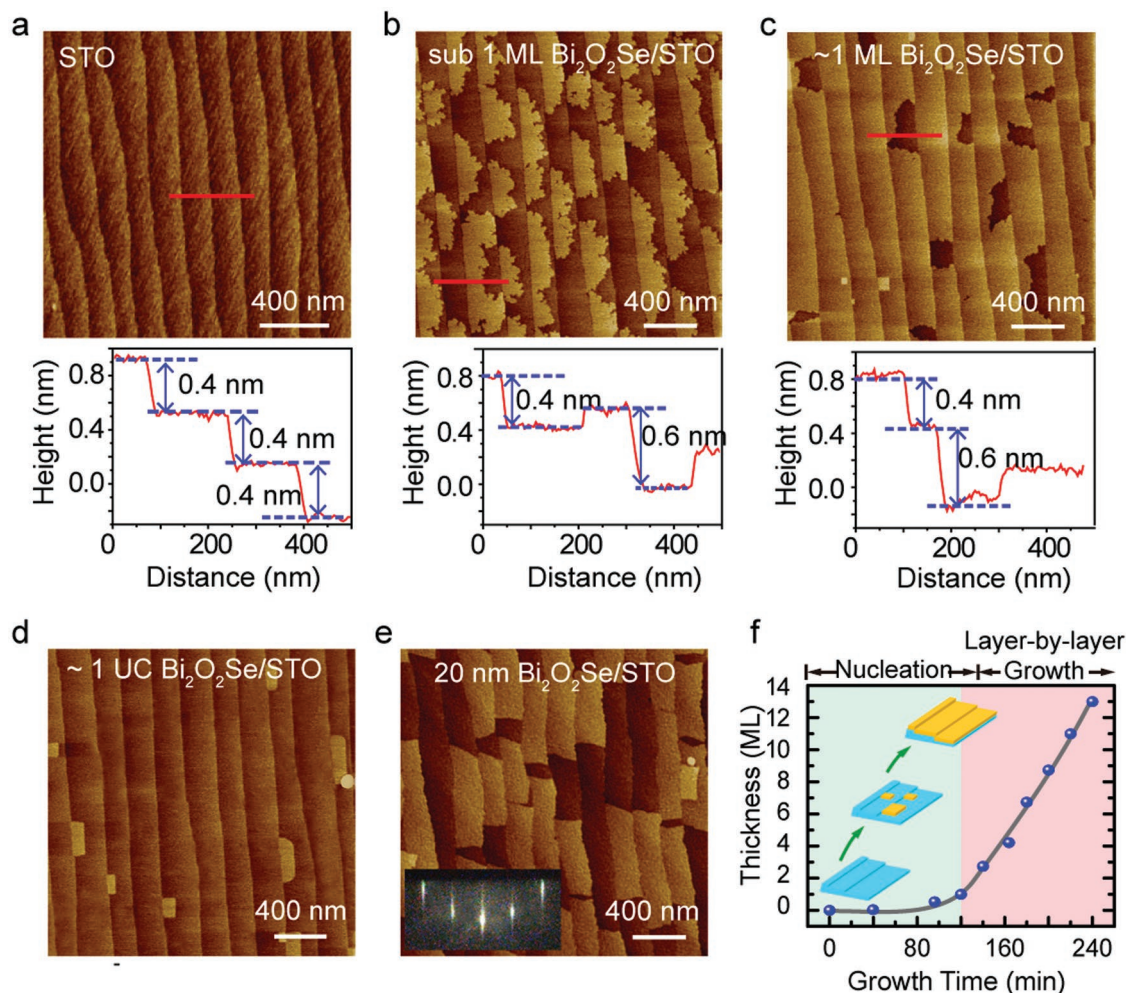


Figure 2. Precise thickness control of $\text{Bi}_2\text{O}_2\text{Se}$ films grown on STO substrate by MBE. a) Surface morphology of TiO_2 -terminated STO substrate, showing clear terraces with a step height of 0.4 nm. b–e) AFM topography of MBE-grown $\text{Bi}_2\text{O}_2\text{Se}$ films with variable thicknesses, showing the morphological evolution of $\text{Bi}_2\text{O}_2\text{Se}$ films from: b) the isolated islands nucleated along the terraces of STO substrate, to c) monolayer (1 ML) $\text{Bi}_2\text{O}_2\text{Se}$ film, to d) 1-UC (2 ML) thick $\text{Bi}_2\text{O}_2\text{Se}$ film with new 2D islands formed on the step edges, and to e) 20 nm thick $\text{Bi}_2\text{O}_2\text{Se}$ film. The MBE growth adopts a 2D growth mode, showing clear terrace heights of 0.4 and 0.6 nm originating from STO substrate and $\text{Bi}_2\text{O}_2\text{Se}$ monolayer, respectively. Inset: reflective high-energy electron diffraction (RHEED) pattern of the surface. f) The thickness of MBE-grown $\text{Bi}_2\text{O}_2\text{Se}$ films as a function of growth time, consisting of initial nucleation stage at first ≈ 100 min and nearly linear growth stage followed.

Further increasing the growth coverage, new 2D $\text{Bi}_2\text{O}_2\text{Se}$ islands with the height of 0.6 nm nucleate at lower terrace edges of the $\text{Bi}_2\text{O}_2\text{Se}$ layer (Figure 2d). Compared with the first layer, the edges of these 2D islands on $\text{Bi}_2\text{O}_2\text{Se}$ layers are regular and parallel to each other, whose orientations register the in-plane lattice direction of STO substrate. The growth of $\text{Bi}_2\text{O}_2\text{Se}$ film maintains the 2D growth mode on STO substrate, until a complete 1-UC thick $\text{Bi}_2\text{O}_2\text{Se}$ film is formed with clear surface step terraces (Figure 2d and Figure S2a, Supporting Information). A thick $\text{Bi}_2\text{O}_2\text{Se}$ film (≈ 20 nm) can be obtained by extending the growth (Figure 2e and Figure S2b, Supporting Information). Reflective high-energy electron diffraction (RHEED) (inset of Figure 2e) captured in vacuum shows sharp streaky pattern, indicating the existence of smooth and long-range ordered surface. The single crystallinity of the film has been confirmed by low energy electron diffraction (LEED) and X-ray diffraction (XRD) (Figure S3, Supporting Information). It is worth noting

that the effective growth rate is nonlinear upon time. Figure 2f illustrates the film thickness as a function of growth time. With fixed growth parameters, the first layer growth spends nearly 2 h, while the growth rate increases to ≈ 20 min per 1 ML and keeps almost constant for the growth of the following layers. This observation reveals that homoepitaxy of $\text{Bi}_2\text{O}_2\text{Se}$ is favored much more than heteroepitaxy on STO.

To further study elemental compositions and atomic alignment of MBE-grown $\text{Bi}_2\text{O}_2\text{Se}/\text{STO}$ interface, we performed the systematic characterization of cross-sectional aberration-corrected STEM on the sample (Figure 3). High-angle annular dark-field (HAADF)-STEM images show an atomically sharp interface between $\text{Bi}_2\text{O}_2\text{Se}$ and STO (Figure 3a,b), where strongly bonded heterointerfaces with a strict epitaxial growth are revealed. Additionally, the geometric phase analysis (GPA) is applied on the HAADF image to elucidate whether or not there is interfacial stress in the epitaxial film (Figure 3c,d). The strain

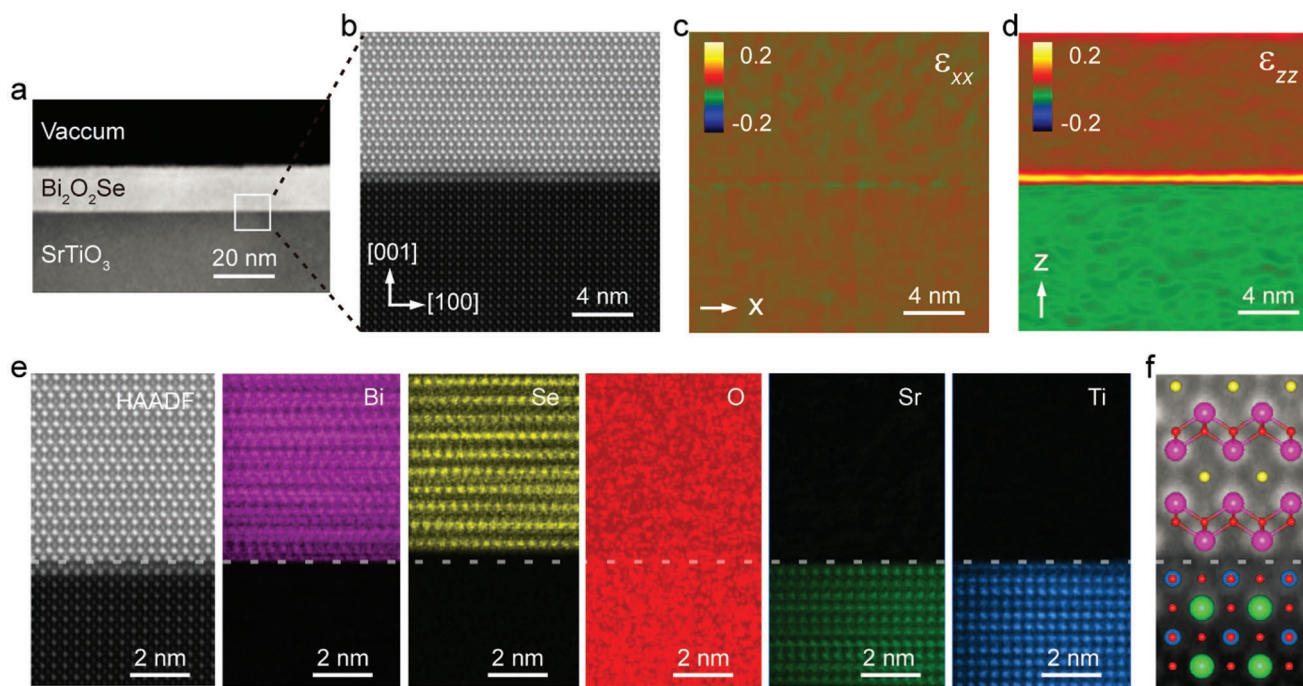


Figure 3. Cross-sectional TEM characterization of MBE-grown $\text{Bi}_2\text{O}_2\text{Se}$ on STO. a) Cross-sectional HAADF-STEM image of the interface between $\text{Bi}_2\text{O}_2\text{Se}$ film (≈ 20 nm) and STO. b) Atomic-resolution HAADF-STEM image of the interface, corresponding to the white box in (a). c,d) GPA of the HAADF image in (b) with uniaxial strain components ϵ_{xx} (c) and ϵ_{zz} (d). All the strain analysis is in reference to the crystal lattice of STO. e) Atomically resolved elemental maps of Bi, Se, O, Sr, and Ti across the interfaces by EDS. f) HAADF-STEM image of the interface with atomic model placed on.

map along x -axis parallel to STO (100) reveals that $\text{Bi}_2\text{O}_2\text{Se}$ film has identical lattice spacing to that of the STO. This observation indicates that the $\text{Bi}_2\text{O}_2\text{Se}/\text{STO}$ interface is nearly free of in-plane misfit strains and dislocations, which results from the perfect in-plane lattice match of $\text{Bi}_2\text{O}_2\text{Se}/\text{STO}$. Along the z -axis parallel to STO (001), the lattice spacing is homogenous in the $\text{Bi}_2\text{O}_2\text{Se}$ film while increases significantly in the first layer near the interface, presumably originating from the larger spacing between first layer of $\text{Bi}_2\text{O}_2\text{Se}$ and STO. Atomically resolved EDS is further performed to investigate atomic arrangements at the interface. Figure 3e shows maps for bismuth (Bi), selenium (Se), oxygen (O), strontium (Sr), and titanium (Ti), respectively, which unambiguously unveils the perfect atomic arrangements of the interface. Layered $\text{Bi}_2\text{O}_2\text{Se}$ contains a stacked structure of $\text{Bi}_2\text{O}_2\text{-Se-Bi}_2\text{O}_2\text{-Se}$. The Bi atoms of $\text{Bi}_2\text{O}_2\text{Se}$ are clearly aligned with Sr at the interface between the $\text{Bi}_2\text{O}_2\text{Se}$ and the TiO_2 -terminated STO (Figure 3f), indicating a perfect epitaxial match.

The 2D epitaxy of high-quality $\text{Bi}_2\text{O}_2\text{Se}$ films on conducting Nb-doped STO via MBE allows direct observation of electronic band structures of atomically thin $\text{Bi}_2\text{O}_2\text{Se}$ by ARPES. The UHV condition during MBE can ensure the clean surface with no contaminations and environmental degradation of the MBE samples. A vacuum suitcase with base pressure lower than 1×10^{-8} mbar was used to keep the film surface fresh during sample transfer process from the MBE chamber to the ARPES system. As shown in Figure 4a,b, ARPES measurements were carried out on MBE-grown 1-UC (bilayer) $\text{Bi}_2\text{O}_2\text{Se}$ films with photons of 21.2 eV from a helium-discharging lamp. Figure 4c-i,ii shows the photoemission spectra intensity maps at the valance band maximum (VBM, or $E_F - 1.06$ eV) and

VBM $- 0.4$ eV, respectively. We observe a warped square near the VBM, which splits with increased binding energy. Figure 4d presents the general high-symmetry band dispersions along $\bar{\Gamma}-\bar{X}$ and $\bar{X}-\bar{M}$, which is dominated by two hole-like bands α and β near VBM around \bar{X} point. In the stacking plots of constant energy contours (Figure 4b), the evolution of this two hole-like bands at higher binding energy is clearly observed. By magnifying the spectra around $\bar{\Gamma}$ near the Fermi level, we observe weak intensity from the bottom of the conduction band, as shown in the inset of Figure 4d,e, indicating the existence of an indirect bandgap in $\text{Bi}_2\text{O}_2\text{Se}$. We do not observe any in-gap states such as the pinned impurity state throughout the whole 2D Brillouin zone, indicating high quality of MBE-grown 1-UC $\text{Bi}_2\text{O}_2\text{Se}$ film.

In order to quantitatively extract the crucial indirect bandgap, we performed surface potassium dosing to raise the Fermi level of the system so that the conduction band minimum (CBM) can be accurately determined. Figure 4f-i) shows the band structure along $\bar{X}-\bar{\Gamma}-\bar{X}$ direction after potassium dosing, with the Fermi level raised about 100 meV compared with the pristine film shown in Figure 4e. The downward shift of the conduction band as shown in the inset of Figure 4f-i), enables us to acquire the details of the dispersion of the conduction band (the appended red curve). By fitting the dispersions around the band bottom with parabolic curve (the appended green curve), we can extract the in-plane ($k_x - k_y$) effective mass m^* of the conduction band, and m^* is estimated to be $\approx 0.15 m_0$, with m_0 denoting the bare electron mass, which is lower than the values in typical semiconductors such as silicon^[33] and MoS_2 ,^[34] but slightly larger than the value in bulk $\text{Bi}_2\text{O}_2\text{Se}$. From the energy

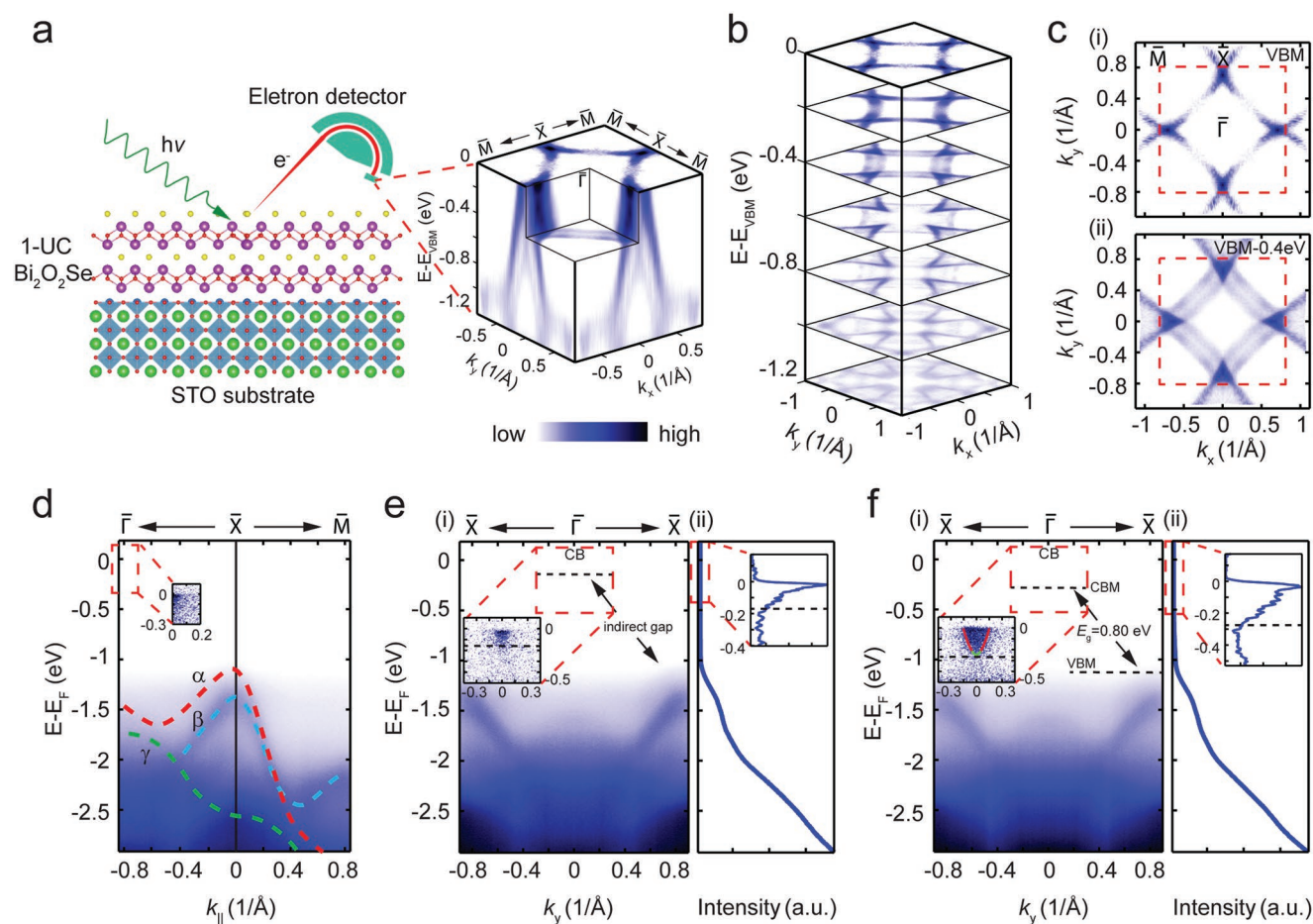


Figure 4. Electronic structures of MBE-grown 1-UC $\text{Bi}_2\text{O}_2\text{Se}$ film. a) Schematic illustration of 1-UC thick $\text{Bi}_2\text{O}_2\text{Se}$ film detected by ARPES with photons of 21.2 eV from a helium-discharging lamp. b) Stacking plots of constant energy contours in broad energy range showing the band structures evolution. c) Photoemission spectral intensity maps of the constant energy contours of bands at i) VBM and ii) VBM-0.4 eV, respectively. Integration over an energy window of 40 meV is included. Red dashed line is the projected Brillouin zone of the (001) surface of $\text{Bi}_2\text{O}_2\text{Se}$ crystal, with high-symmetry points of Brillouin zone labeled. d) Band dispersions along $\bar{\Gamma}$ - \bar{M} of MBE-grown 1-UC thick $\text{Bi}_2\text{O}_2\text{Se}$ film, with three main valance bands labelled by α , β , and γ , respectively. e, f) Band dispersions along \bar{X} - $\bar{\Gamma}$ - \bar{X} direction (i) and corresponding EDCs (ii) before (e) and after (f) surface potassium dosing, an indirect energy gap of ≈ 0.8 eV is clearly observed. Insets are zoom-in plots of conduction band and corresponding EDC with long-time integrated.

distribution curve (EDC) shown in Figure 4f-ii), we obtain the CBM at $E - E_F = -0.26$ eV and the VBM at $E - E_F = -1.06$ eV. Thus, the indirect bandgap equals ≈ 0.8 eV for the 1-UC $\text{Bi}_2\text{O}_2\text{Se}$ film, in consistence with previous bulk measurements.^[9]

In order to give a reasonable comparison between epitaxial thin film and bulk single crystal, we also conduct systematic ARPES measurements on bulk $\text{Bi}_2\text{O}_2\text{Se}$ crystal using the same experiment setup (details can be found in the Supporting Information). The constant energy maps show nearly the same warped-square structures as on the MBE-grown 1-UC $\text{Bi}_2\text{O}_2\text{Se}$ film. However, the spectrum is surprisingly more blurred than on the MBE film, suggesting that the crystal quality of our MBE film is even higher than the bulk material. As to the situation of band dispersions, the main α , β , and γ bands in bulk crystal are clearly observed, displaying similar dispersion shape with those in 1-UC film. However, despite nearly the same dispersion shape and intensity of α and β bands around \bar{X} point, we find that the intensity of these three bands around $\bar{\Gamma}$ is strongly suppressed in the thin film. The different behaviors

of the bands around $\bar{\Gamma}$ and \bar{X} points strongly hint its origin of different orbital components. The thickness-dependent bands around $\bar{\Gamma}$ suggest it originates from delocalized out-of-plane orbitals, while thickness-independent bands around \bar{X} indicate they are mainly formed by localized in-plane orbitals, which is quite consistent with the GGA calculations by Wu et al.,^[9] the dominant orbitals of valance bands are Se p_z and Se $p_{x/y}$ around $\bar{\Gamma}$ and \bar{X} , respectively. We note that the overall observed bands shift upward about 40 meV in the bulk crystal, indicating the slight electron-doping in the as-grown thin film. The indirect bandgap of ≈ 0.74 eV in the bulk material is obtained from potassium dosing result, smaller than that in the thin film, which is qualitatively in good agreement with the tendency of thickness-dependent gap evolution evaluated by GGA calculations. We also extract the effective mass of about $0.10 m_0$ of the conduction band, smaller than that of $0.15 m_0$ in the thin film, which is quite consistent with the calculation results of $0.12 m_0$ for bulk material while $0.16 m_0$ for bilayer film by Wu et al.,^[9] the dominant orbitals of valance bands are Se p_z and Se $p_{x/y}$

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In conclusion, we have demonstrated the MBE-growth of atomically thin Bi₂O₂Se films down to monolayer by co-evaporating Bi and Se precursors in oxygen atmosphere. With optimized conditions, the growth adopts a 2D growth mode and precise thickness control has been achieved. Besides, the MBE-grown high-quality Bi₂O₂Se on STO shows an atomically sharp interface and atom-to-atom alignment. Using ARPES, the electronic structures of MBE-grown 1-UC (bilayer) Bi₂O₂Se films were successfully observed, displaying low effective mass of $0.15 m_0$ and very slightly bandgap enlarging compared to bulk one.

Additionally, in view of practical device applications, it would be better to grow atomically thin Bi₂O₂Se film on insulating SrTiO₃ substrate (as shown in Figure S5, Supporting Information), whose heating mode should be changed and precise substrate treatments are needed to avoid the undesirable formation of oxygen vacancies under vacuum heating. Besides, theoretical calculation results predict that the thermoelectric performance can be significantly improved by application of tensile strain on monolayer Bi₂O₂Se.^[35] Theoretically, the tensile strain in MBE-grown Bi₂O₂Se film can easily be tuned through changing the epitaxial substrate from SrTiO₃ to piezoelectric PMN-PT,^[36] whose lattice parameter can be gradually tuned by applying an external voltage bias. These topics need further research in the future.

Supporting Information

Supporting Information is available from the Wiley Online Library or from the author.

Acknowledgements

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corrected electron microscope. H.L.P., J.D.G., H.T.Y., and Y.L. conceived the experiments. Y.L., C.W.T., and X.F.X. carried out the synthesis and structural characterizations. Y.W.S. performed the cross-sectional TEM under direction of P.G. Y.J.C., L.X.Y., and Y.L.C. performed the ARPES characterizations. H.L.P., Y.L., Y.J.C., J.X.W., and S.P.X. wrote the manuscript. The whole work was supervised by H.L.P. and J.D.G. All authors discussed the results and commented on the manuscript.

Conflict of Interest

The authors declare no conflict of interest.

Keywords

2D materials, Bi₂O₂Se, molecular beam epitaxy, oxchalcogenides, ultrathin films

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